Transaction Information

Tool ID	MIMP-A13
Tool Status	Connected
Location	Woodlands, Singapore
Wafer Size	200 mm
Fab Section	Implant
Tool Available Date	2024-11-30

General Product Information

Vendor Supplier	AXCELIS TECHNOLOGIES
Model	NV-GSD/HE
Vintage	2003
Serial No	090253
Asset Description	F067PE0526M0X03
Software Version	5.12.8
CIM	GEM SECS
Process	ION IMPLANTATION SYSTEM

Hardware Configuration (Fab)

System Type	Description	Quantity	Status
Main System	MAIN UNIT	1	OK
Handler System	OEM STANDARD ARM	1	OK
Factory Interface	SMIF	1	OK
Options System			
Others			

Hardware Configuration (Subfab / Auxilliary Units)

Description	Quantity	Status
SCRUBBER EXHAUST	1	OK
		OK
		OK
HEAT EXCHANGER	1	OK

Missing/Faulty Parts / Accesorries List

Description	Quantity
ALL MISSING PARTS NOT FOR SELLING	
P5 TURBO PUMP	1
CRYO P3	1
RP4 DRY PUMP	1
RP2 DRY PUMP	1
SYSTEM HARD DISK	1
CRYO P2	1
RESONATOR #5	1
RP1 DRY PUMP	1
AUXILIARY SUN2	1
P4 TURBO PUMP	1
DISK CHILLER	1

Description	Quantity
LPT 2200 SMIF	1
CRYO P9	1
RESONATOR #3	1
CRYO COMPRESSOR	2
P8 TURBO PUMP	1

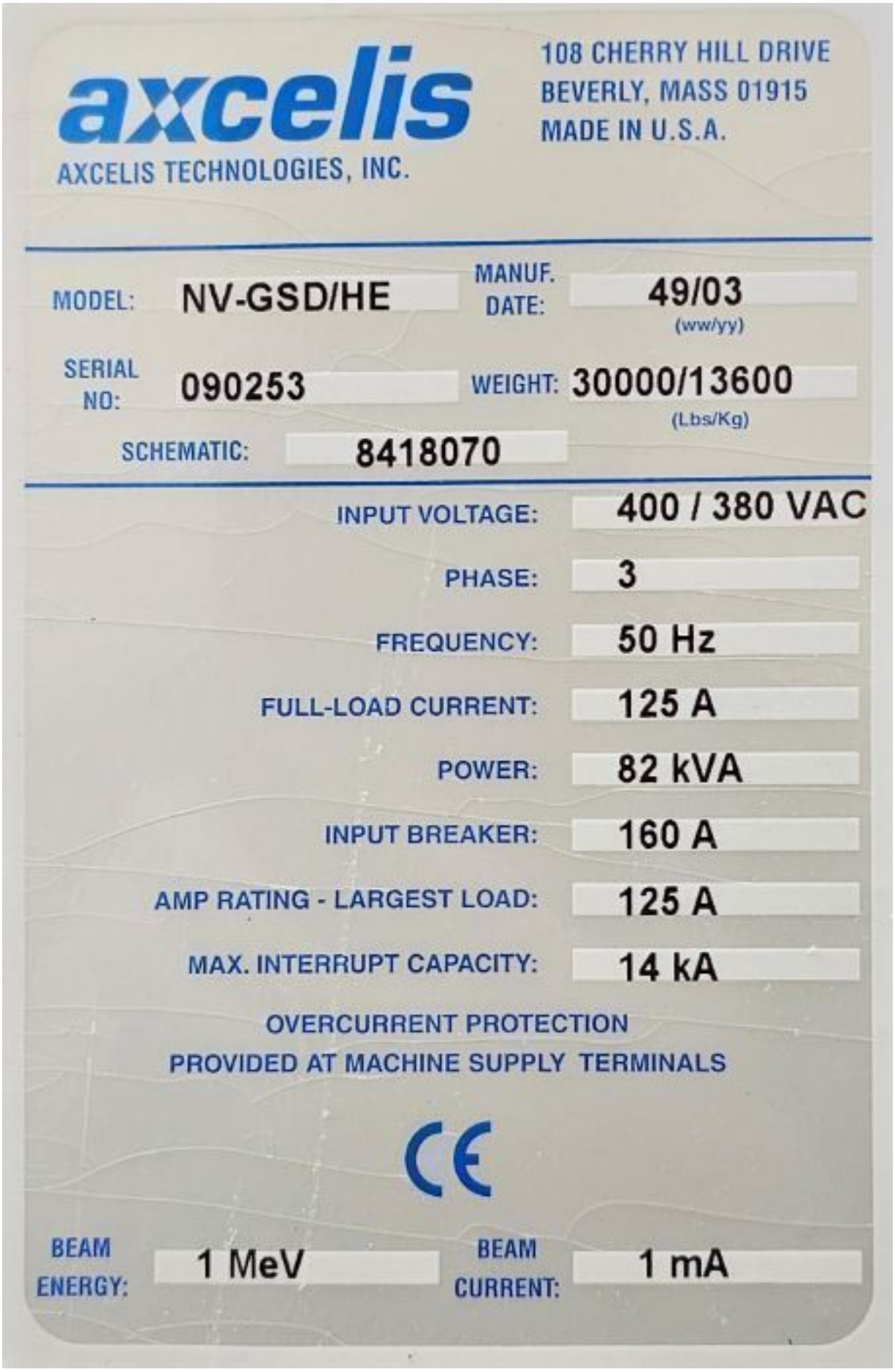
Tool Pictures

General	MAIN TOOL

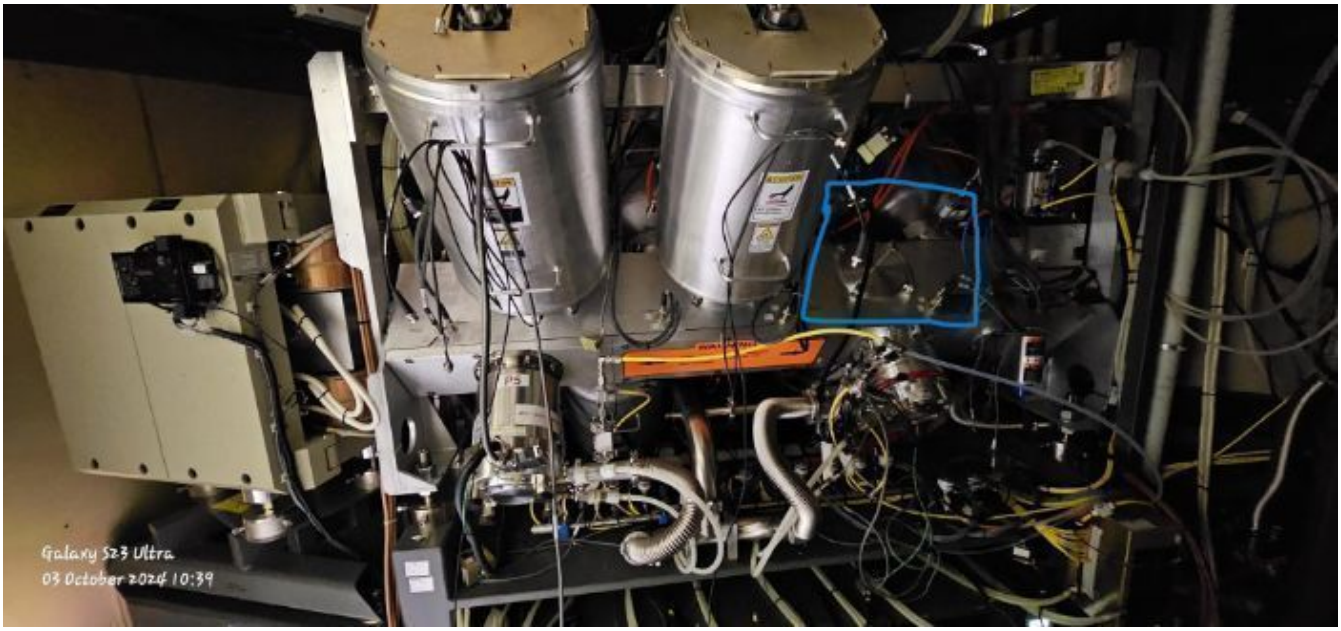
Hardware Sub-fab	AUXILLIARY UNITS

Hardware Sub-fab	AUXILLIARY UNITS

Manufacture Serial	TOOL TAG

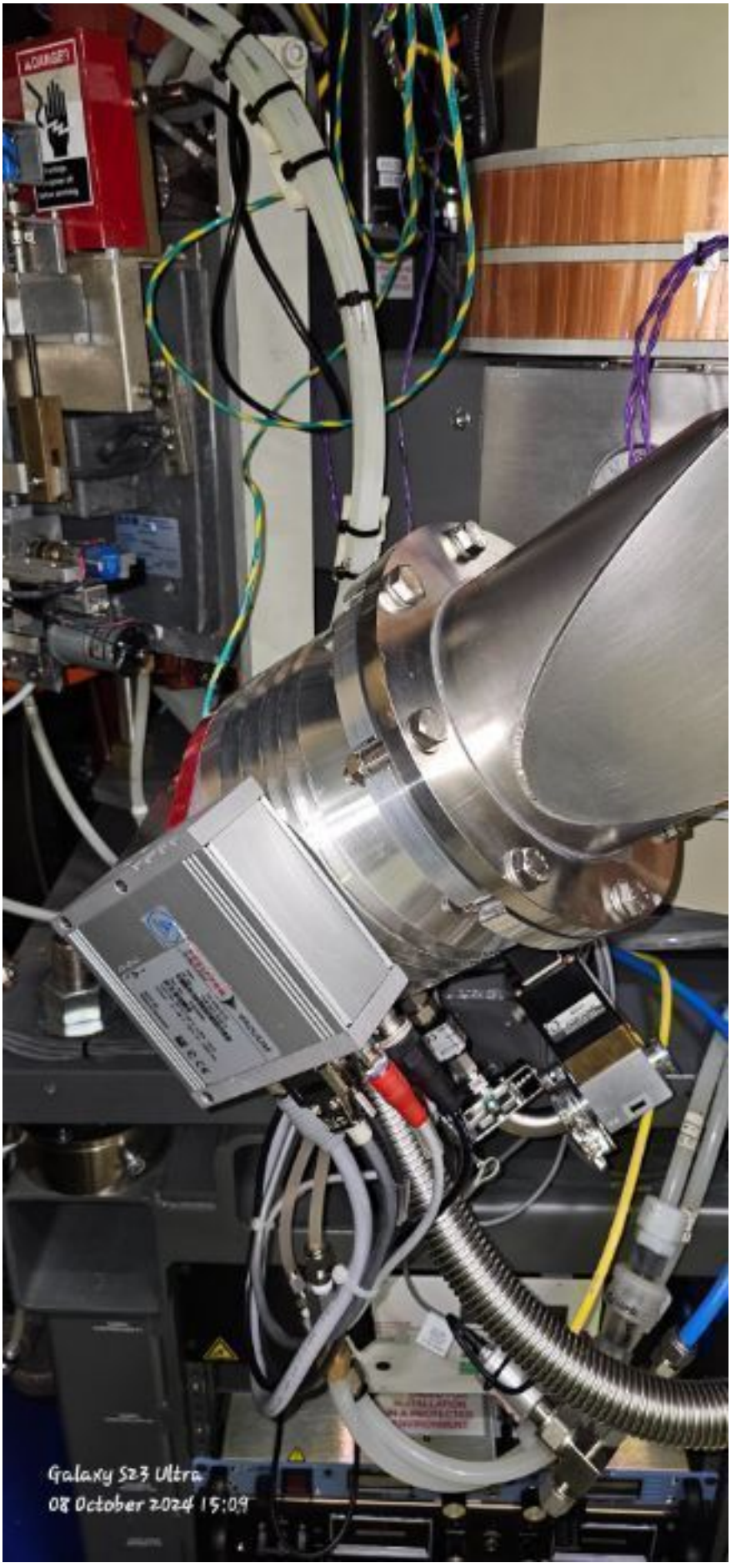


Missing Parts	MISSING PARTS



Missing Parts	MISSING PARTS

Missing Parts	MISSING PARTS



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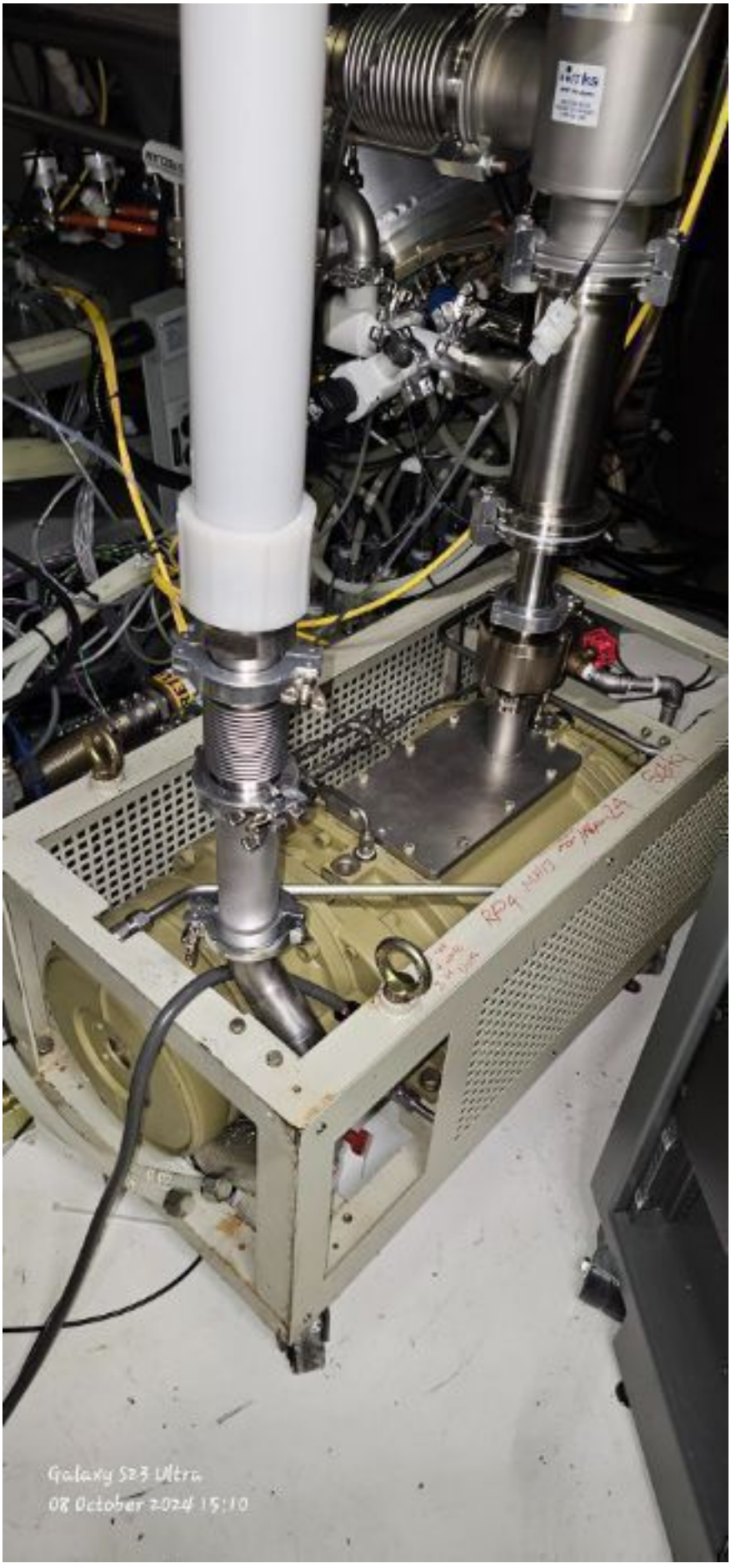
Missing Parts	MISSING PARTS



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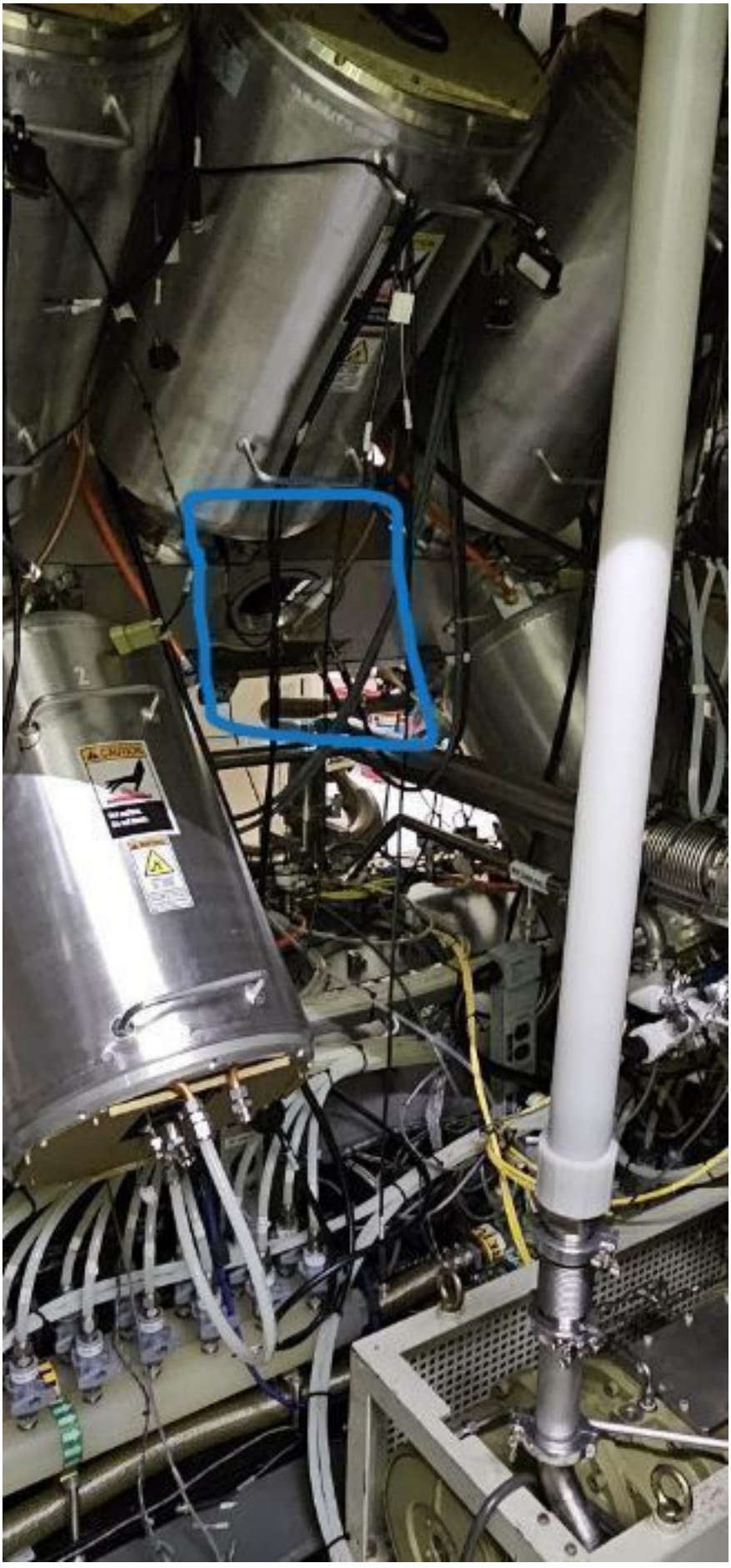
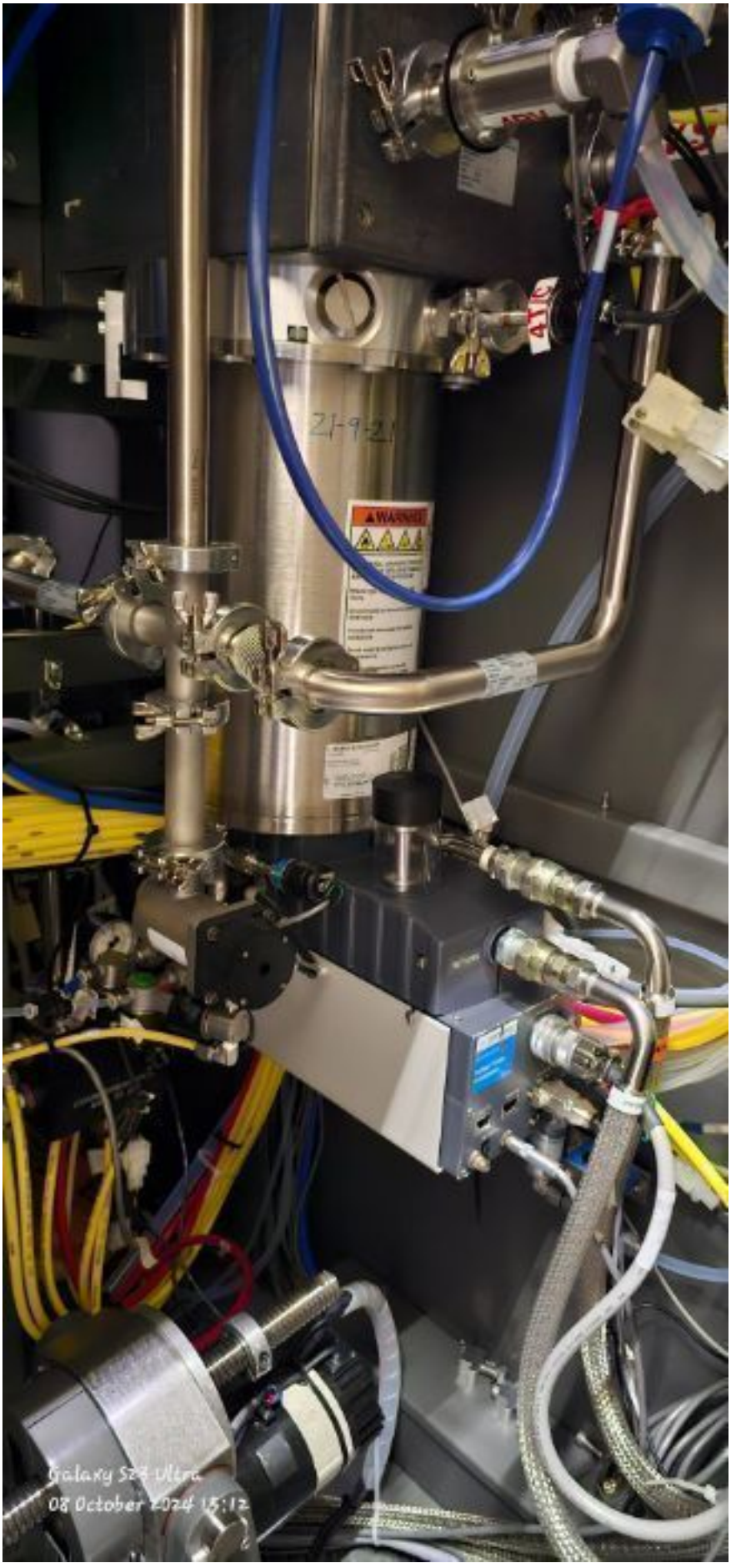
Missing Parts	MISSING PARTS

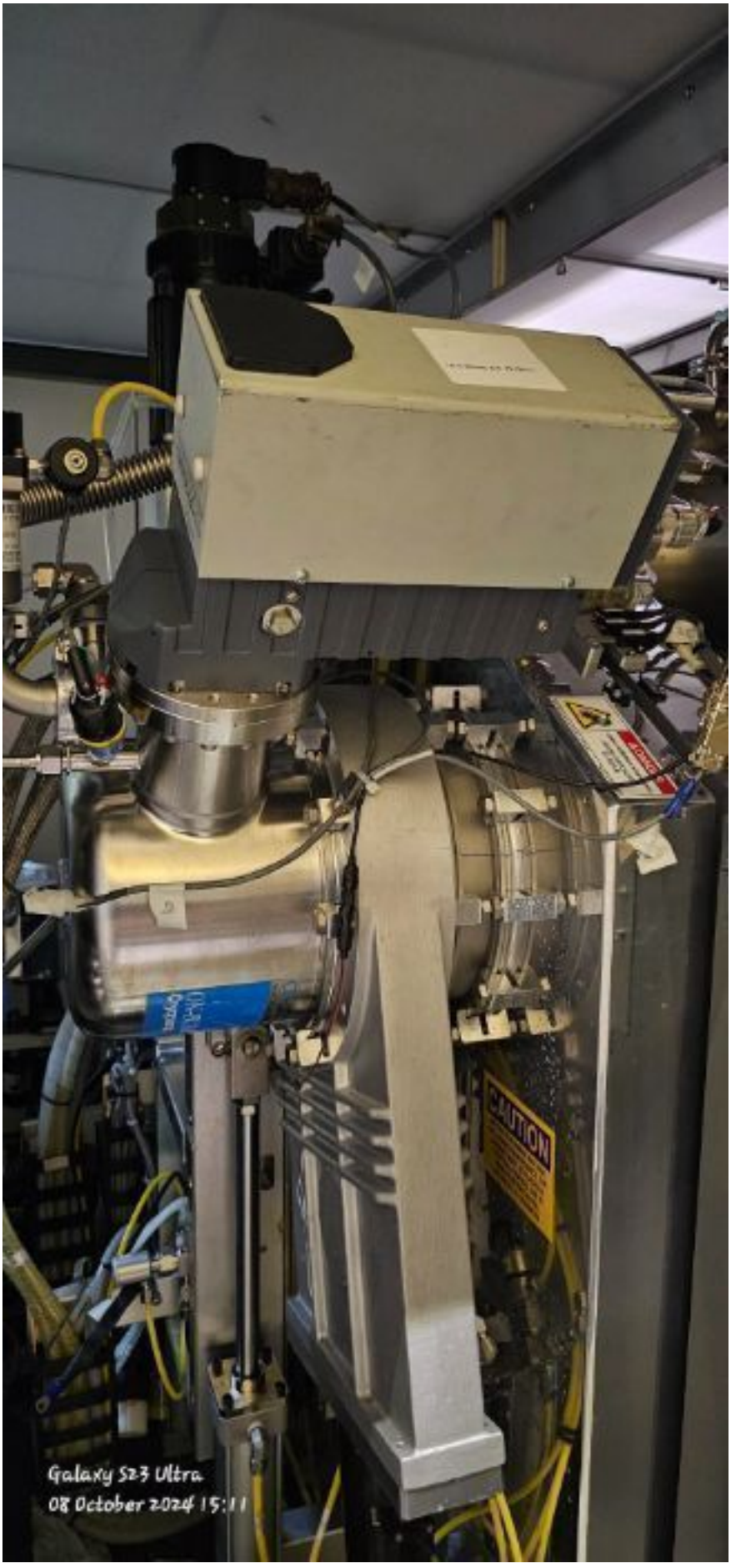


Missing Parts	MISSING PARTS

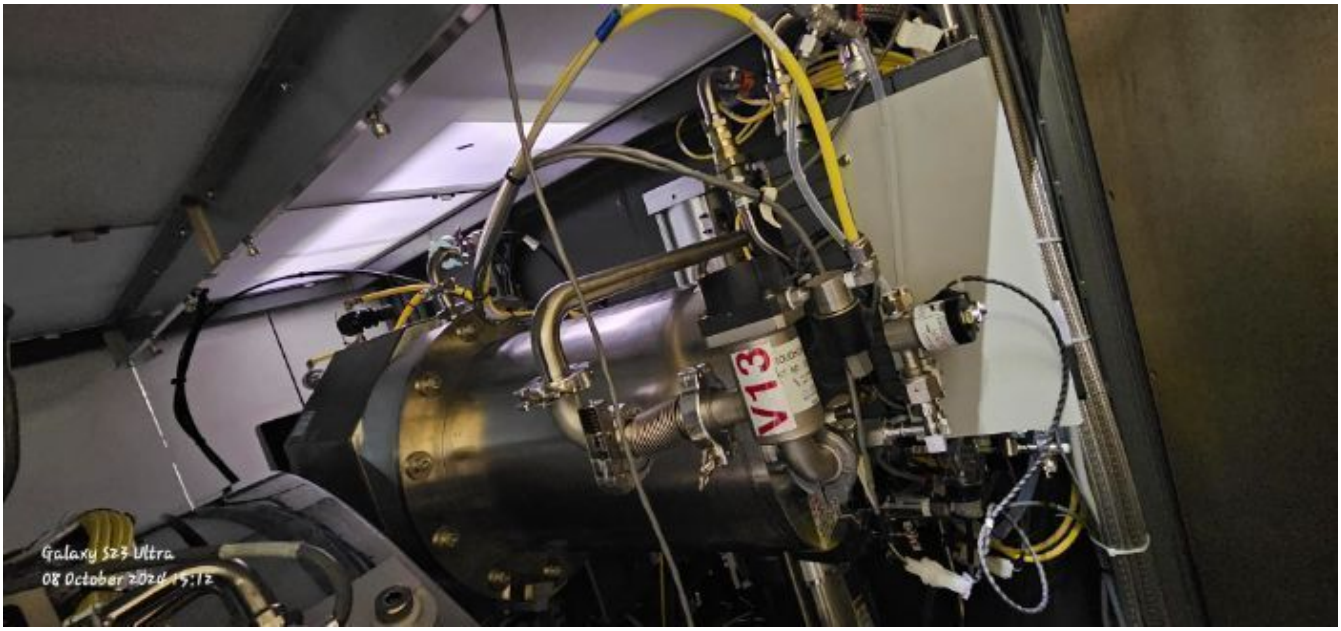


Missing Parts	MISSING PARTS

Missing Parts	MISSING PARTS



Missing Parts	MISSING PARTS



Additional Tool Data Files

		MIMPA13
!P9 Cryo Pump Type	104	2
!External Alarm Box	106	
!Wafer Barcode Reader Present	107	
!Main PD Varistor Present	108	1
!Machine type	109	
!Iso Transformer Temp Sensor Present	110	
!End station cassette door installed	111	
!Source Cleaning Tube Present	113	
!Source region vacuum pump type	115	1
!Gas bottle controllable valves installed	117	
!Remote roughing pump system installed	119	
!N2 hi-low pressure gauge readbacks installed	122	
!Gyro present	123	1
!Barcode reader installed	124	
!Slot to Slot Integrity	125	
!Gas system type	126	107
!Selectable Cryo Exhaust Valve Present	127	
!HYT particle sense installed	129	
!Loadlock Type	132	
!GSD Disk Type	133	2
!SMIF Arm Present	134	1
!SMIF SAM Present	135	1
!V3 Safe Sensor Present	137	1
!Gyro Type Selection	138	
!Light Pen Present	139	
!Extr Electrode Manipulator	140	2
!Controller Type for IG1	142	360
!Controller Type for IG2	143	360
!Controller Type for IG3	144	360
!Controller Type for IG4	145	360
!Controller Type for IG5	146	
!RP2 Pump Type	147	2
!Source Type	148	4
!Beamline Cryo Pump Type	149	2
!RP1 Pump Type	150	2
!Light Pen Active for Sun1	151	
!Light Pen Active for Sun2	152	
!Light Pen Active for Sun3	153	
!FF Burnthru Hardware Present	157	
!UPS Present	158	

!SMIF Pod Cassette Sensor Present	159	
!Beam Profile Holes Type	160	1
!P4 Turbo Pump Type	162	1
!P5 Turbo Pump Type	163	1
!RP4 Pump Type	164	2
!Elec Shower Aperture Sensor	165	1
!IG3 Location	167	1
!Vac G1 Isol V31 Present	168	
!Electron Shower Present	170	1
!Water Panel Type	171	3
!AGV Present	172	
!RP1 Nitrogen Sensor Present	173	
!Sonic Sensor Present	175	
!Cassette Table Type	176	2
!Shower Gas Type	179	
!P6 Turbo Pump Type	183	666
!P7 Turbo Pump Type	184	666
!P8 Turbo Pump Type	185	2
!Elec. Stat. Quad Present	186	
!Shower Gas Panel Assembly Type	187	
!Electron Shower Gas Panel Present	188	1
!Cassette Door Switch 2	192	
!Cassette Type	195	
!Gyro Amp Type Selection	199	2
!Customer Interlock Present	3104	
!Top Loader Present	3125	
!Pre-Spin Disk	3144	
!Dose check enable	3145	
!Dose check limit	3146	90
!ES Safety Hardware Interlock	3162	
!Roughing Pump Delay	3164	
!Beam Noise Sensor Present	3165	
!SPC Violation Alarm/Hold	3166	
!Slow vent delay time	3170	
!Hardware Inlk Alarm Type	3179	1
!Gyro Alpha Angle Correction	3186	
!Gyro Beta Angle Correction	3187	
!Disk Chiller Temperature Monitor	3188	
!Disk Vibration Control Type	3192	
!Disk Vibration Control Value	3193	1000
!AMU FEM Water Flow Switches Present	3194	

!Source Cathode Power Supply Type	3197	
!On-Disk Beam Angle Detector	3199	
!Beam Spectrum Analyzer Present	3200	1
!Enable BCR Check Levels For Manual TBL-to-VCSS	3802	
!Elevator Motor Speed Level	3806	5
!Arm Motor Speed Level	3810	5
!Loadlock Slow Rough delay time	3813	
!Arm Motor Acceleration Level	3815	5
!Manual to Auto Endstation Transition Acknowledgment	3819	
!End Station Auto Mode Auto-init Acknowledge	3821	
!ES DI Comm Loss Pop Up	3822	
!Wafer ID Ignore Length	3823	
!Wafer Barcode Type	3829	1
!Backup Options	3830	
!Stand Motor Speed Level	3832	5
!Loadlock Rough Threshold Setting	3833	250
!TOF Energy Measurement System	3835	
!TOF Energy Measurement Setup Value	3836	115.8
!FEM Calibration Rules Version	3837	1
!Rotary Drive Acceleration	3847	
!FEM Faraday Present	3842	
!Beam Angle Mask Present	3851	
!LINAC VCXO error detection	3852	
!Pre-Implant Gyro Movement Verification	3854	
!Enable Wafer Alignment Security Feature	3855	
!InVac Disk Wafer Load Method	3861	
!Disk Vibration Monitor Delay	3862	8
!Enable H2 or H2/Kr Carrier Gas	3863	
!Reflected Power Limit	3864	225
!Hold Implant on CEX Lock Status Error	3865	1
!Maximal extraction voltage	201	100000
!Maximal post-acceleration voltage	202	5000000
!Plsm fil current offset	203	
!Wafer Pre-Aligner Calibration Offset	206	
!Wafer type	207	1
!Wafer size	208	5
!Continuously Variable Aperture	209	
!CVA Defining Aperture Size (mills)	210	160
!Load lock arm to cassette offset	222	50
!Load lock arm to disk offset	223	-85
!Load lock elevator offset	224	200

!Load lock stand offset	225	125
!Number of Resonators	233	10
!Number of Quad Power Supplies	234	10
!Type of Resonators	235	1
!Number of Slots/Cassette	239	25
!Facilities Water Leak Fault Action	240	1
!Facilities Toxic Gas Fault Action	242	2
!Cryo Cooling Type	243	
!SMIF Arm Pre-Load Enable	244	
!SMIF Arm Pre-Unload Enable	245	
!Dual final hall present	247	
!Dual final hall reading pct diff limit	248	1
!Wafer Handling Arm Chuck Test Enable	249	
!Wafer Handling Wafer Holder Chuck Test Enable	250	
!Post Implant Pad Sense Needed	253	
!Beta Beam Angle Detector Offset Value	260	
!Beam Angle Detector Max Gyro Correction	261	1
!InVac DI Amplifier Type	264	
!InAir DI Amplifier Type	265	
!Robot DI Amplifier Type	266	
!Rotary DI Amplifier Type	267	
!Alpha Beam Angle Detector Offset Value	270	
!Gyro Range for Beam Angle Scan	272	
!Plasma Shower Standby Gas Flow	273	0.2
!Interlock Level	274	2
!BAC Measure Only Implant Interlock	275	
!Beam Angle Control Scheduling Method	276	
!Beam Angle Control Scheduling Index	277	
!Beam Angle Control Scheduling Time	278	
!Pre-Implant Beam Noise Check Enable	279	
!Pre-Implant Beam Noise Limit(mA)	280	100
!Improved Linac ramp up handling of Reflected Power	281	
!Wafer Barcode Override	406	
!Loop1 Of Triple Loop Chiller/Triple Loop Heat Exchanger Connected	407	1
!Display beam quality factor	408	1
!Active Passive Control	409	
!Operator Interface Language	410	
!Customer's Native Language	411	
!Gem Pop-up Text Enabled	412	1
!Active/Passive Sun2 Control Request Needed	413	
!Auto logout wait minutes (0 is inactive)	414	

!Abort Recipe View Option	415	
!Beam tuning mode	501	1
!SMIF SECS Host Pass Thru Enable	502	1
!Implant mode	503	1
!P9 Vac rate of rise retries	504	20
!P9 Cryo rate of rise test val	505	10
!P9 Cryo crossover press val	506	70
!P9 Extended Purge Time	507	120
!Seconds for Power Fail Recovery	508	300
!Seconds to Power Fail Regen	509	600
!Extr. Load Compensation Enable	510	1
!Duplicate Lot Checking File Size	511	4
!Dose PComp Algorithm Type	512	
!Wafer Barcode Check Levels	515	
!Auto Resume - plasma shower error	517	
!Auto Resume - rotary drive speed error	518	
!Auto Resume - low beam current	519	
!Auto Resume - flag faraday error	520	
!Auto Resume - beam energy error	521	
!Auto Resume - general vacuum system error	522	
!Auto Resume - process recipe limit error	523	
!Auto Resume - start vacuum error	524	
!Auto Resume - vacuum exceeds stop pressure	526	
!Auto Resume - linear drive error	527	
!Auto Resume - dose DI communication error	528	
!Auto Resume - high linear drive speed	529	
!Auto Resume - electron shower error	530	
!Auto Resume - dose DI hardware error	531	
!Auto Resume - low beam line pressure	532	
!Auto Resume - high beam line pressure	533	
!Auto Resume - end station vacuum error	534	
!Delay for automatic resume (seconds)	535	
!AB argon cleanup btwn species minutes	536	2
!AB argon cleanup for shutdown minutes	537	3
!AB spray argon during cleanup	538	1
!Autobeam shutdown mode	539	1
!Enable automatic implant beam recovery	540	1
!Status Beacons Present	542	
!Select ion gauge for pressure compensation	543	1
!Enable automatic beam park	544	
!Unpark Beam with n wafers left to unload	545	
!HYT Halt Threshold	546	999999999

!HYT Start Hold Threshold	547	999999999
!Auto Beam Standby Enabled	548	1
!SMIF Arm Secs Device Id	549	868
!SMIF SAM Secs Device Id	550	100
!Auto Beam Wakeup Enabled	551	
!Auto Beam Sleep Enabled	552	
!Auto Beam Shutdown Pumpdown Src Press	553	0.00002
!HYT Bin Size Threshold	554	75
!P2 Vac rate of rise retries	555	20
!P3 Vac rate of rise retries	556	20
!P2 Cryo rate of rise test val	557	10
!P3 Cryo rate of rise test val	558	10
!P2 Cryo crossover press val	559	70
!P3 Cryo crossover press val	560	70
!Gas Auto-Purge Number of Cycles	561	10
!Auto Vap1 Standby Enable	562	
!Auto Vap2 Standby Enable	563	
!Arsenic Standby Temp	564	300
!Phosphorus Standby Temp	565	310
!Antimony Standby Temp	566	250
!SB03 Standby Temp	567	250
!BLIF Standby Temp	568	250
!Vaporizer Temp Boost Enable	569	
!Vaporizer Temp Model Enable	570	
!Audible Alarm on Cass/Pod Complete	571	
!Beam Park Enabled	572	
!Tower Light Mode Options	574	34
!SDS Gas Bottle Pressure Low Warning	576	
!Gas Bottle Pressure Low Warning	577	
!P2 Extended Purge Time	578	120
!P3 Extended Purge Time	579	120
!Pressure Gauge Units Type	580	
!Auto Beam Src Fil Warm Shutdown Enabled	581	
!Auto Beam Latest Phos Vap Temp Enable	582	
!Auto Beam Shutdown Pumpdown MFC	583	1
!Auto Selection of Previous Recipe	585	1
!Electron Shower Prev Impl Gas On	586	1
!SPC Purge Period	587	90
!Extraction Suppression Monitor Enable	588	1
!Plasma Auto Enable	589	1
!End Station Door Event	590	
!Autotune Fast History Startup Enable	591	1
!Alarm Log in IDL	592	1

!AMU Calibration	593	1
!Auto Beam Source Gas Flow History Enable	597	1
!Extraction Suppression Lead Enable	598	1
!Auto Beam Latest As Vap Temp Enable	3501	
!Source Housing Exhaust Valve Present	3518	
!Disk Speed during Implant (RPM)	3533	1210
!Auto Resume - high beam current	3536	
!Glitch Monitor Enable	3537	
!FEM New Calibration Enabled	3538	
!FOM K-FACTOR Enable	3539	1
!Auto Beam Latest SbF3 Vap Temp Enable	3540	
!Autobeam Alarm Verbosity Level	3541	3
!Auto Beam Startup Timeout (Minutes)	3554	
!Auto Beam Latest SbO3 Vap Temp Enable	3560	
!Auto Resume - Injector Faraday in Beam	3561	
!Roughing Pump Stagger - Seconds	3562	
!Disk Faraday Circuit Calibration Enable	3563	1
!Gyro Move Mode	3564	
!Pre-Move Gyro Enable	3565	
!Productivity Enhancement	3566	
!Gamma Pcomp Recipe Rules Type	3584	2
!FEM Setting Tolerance	3585	
!Mini-Environment Monitoring	3586	
!Machine Configuration/Recipe Compatibility Check	3588	
!Pre-Implant Status Check Wait Time	3589	
!IG3 off during LL rough	3590	
!Auto Resume - ES sliding seal press err	3592	
!Imp Hold ES Sliding Seal TC6 Press Limit, mTorr	3593	1000
!Imp Hold ES Sliding Seal TC7 Press Limit, mTorr	3594	1000
!Optimized Fast Scan Enable, Selectable by Recipe	3595	
!Beam Profile Height Max (mm)	3705	106
!Beam Profile Width Max (mm)	3706	106
!Beam Profile Height Offset Up Max (mm)	3707	53
!Beam Profile Height Offset Down Max (mm)	3708	-53
!Beam Profile Width Offset Right Max (mm)	3709	53
!Beam Profile Width Offset Left Max (mm)	3710	-53
!Beam Profile Spot Top Edge Max (mm)	3711	53
!Beam Profile Spot Bottom Edge Max (mm)	3712	-53
!Beam Profile Spot Right Edge Max (mm)	3713	53
!Beam Profile Spot Left Edge Max (mm)	3714	-53
!Minimum Fast Scan Rate (Disk Speed in RPM)	3715	600
!Dose check lower limit	3720	0.8

!Dose check upper limit	3721	1.2
!Beam Profile Offset Correction Mode	3723	
!Linac Resonator Autotune	3724	
!HYT Rotary Trigger Time	3727	1
!Constructive Frequency Tolerance (%)	3731	1
!Special Temperature Flow	3733	
!Process Limit Alarm Suppression Enable	3736	
!Dosimetry check threshold	3737	0.3
!IG1 Pressure High Hold Limit	3738	0.00099
!IG1 Pressure Low Hold Limit	3739	1e-8
!IG2 Pressure High Hold Limit	3740	0.00099
!IG2 Pressure Low Hold Limit	3741	1e-8
!IG4 Pressure High Hold Limit	3742	0.00099
!IG4 Pressure Low Hold Limit	3743	1e-8
!IG3 Min Imp Operate Thresh Pressure	3744	1e-8
!Ion Gauge Recipe Limit Config Default Enable	3745	
!IDL gas bottle pressure	3746	
!XeF2 GasOnly Clean Time	3748	60
!XeF2 Arc Clean Time	3749	60
!XeF2 Extract Clean Time	3750	60
!XeF2 Sweep Clean Time	3751	180
!XeF2 Clean Enable	3752	
!Side Axis Suppression Tuning Enable	3753	
!HYT Violation Implant Resume Option	3755	
!Tune Standby Beam To Injector Faraday Only	3756	1
!FEM optimization, Linac ramp repeat	3758	
!H2 contamination test threshold	601	0.1
!F contamination test threshold	602	0.1
!N2 contamination test threshold	603	0.1
!SECS baud rate	604	9600
!SECS equipment ID	605	1
!SECS max. number of retries	606	3
!SECS timeout #1	607	0.5
!SECS timeout #2	608	10
!SECS timeout #3	609	45
!SECS timeout #4	610	45
!BF2 contamination test threshold	611	0.1
!Max. size of alarm history file	612	8
!Rotary drive's RPM at auto clean	613	300
!Max. retries for auto resume	614	
!SECS data log mode	615	
!Daily Check Auto Logging Time (HHMM)	616	
!Dummy dose warning limit	617	100000000000000000

!Machine Alias Name	618	HE253
!Machine SECS type	619	2
!Machine identification code	620	MIMPA13
!Auto Beam Standby Timeout	621	3
!Auto Beam Shutdown Timeout	622	0.5
!GEM Configuration Alarms	623	
!GEM Configuration Connect	624	2
!GEM Configuration Events	625	1
!GEM Init Comm State	626	
!GEM Init Control State	627	1
!GEM Write Bits 10	628	1
!GEM Write Bits 5	629	1
!GEM Write Bits 6	630	1
!GEM Establish Com Delay	631	1
!GEM Heart Beat	632	1
!Cassette Wait on Table	633	3600
!GEM Report Type	634	
!GEM Device Name	635	NV-20A
!UPS Start Delay	638	60
!Robot transfer radius limit	639	12025
!Extended SECS Mode	640	
!SPC Present	641	1
!Number of Beamless Implant Scans	642	2
!Extraction Suppression Average Shutdown Power	643	700
!Extraction Suppression Monitor Window Time	644	60
!Rotary Motor Off Command Timeout	645	5
!Rotary Initialize Command Timeout	646	30
!Rotary Move Command Timeout	647	20
!Rotary Speed(RPM) Command Timeout	648	40
!Rotary Stop Command Timeout	649	50
!Linear Move Command Timeout	650	30
!Linear Test Scan Command Timeout	651	60
!Gyro Move Command Timeout	652	30
!Robot Initialize Command Timeout	653	40
!Table Initialize Command Timeout	654	40
!Aligner Initialize Command Timeout	655	3
!InAir Multi Wafer Transfer Command Timeout	656	400
!InAir Single Wafer Transfer Command Timeout	657	45
!InAir Hold Robot (Add/Remove Cassette) Command Timeout	658	45
!InAir Control Command Timeout	659	3
!InAir Fixture Command Timeout	660	10
!InAir Table Move Command Timeout	661	8
!InAir Align Command Timeout	662	8
!InAir Data Write Command Timeout	663	15

!Elevator Initialize Command Timeout	664	20
!Stand Initialize Command Timeout	665	50
!Arm Initialize Command Timeout	666	20
!InVac Fixture Command Timeout	667	7
!InVac Chuck Sequence Command Timeout	668	5
!InVac Release Sequence Command Timeout	669	5
!Vent Command Timeout	670	100
!Rough Command Timeout	671	55
!Vent/Rough Sequence Command Timeout	672	75
!InVac Single Wafer Transfer Command Timeout	673	45
!InVac Multi Wafer Transfer Command Timeout	674	375
!Pad Check Command Timeout	675	40
!InVac Auto-initialize Command Timeout	676	120
!InVac Wafer Recover Sequence Command Timeout	677	50
!InVac Control Command Timeout	678	10
!InVac Data Write Command Timeout	679	5
!Smif Arm Load/Unload Command Timeout	680	120
!Smif Arm Home Command Timeout	681	90
!Smif Arm Abort Command Timeout	682	90
!Smif Arm Pod Command Timeout	683	45
!Cassette Access Door Command Timeout	684	3
!Add/Remove Command Timeout	685	200
!AGV Communications Timeout T1	686	60
!AGV Communications Timeout T2	687	60
!AGV Communications Timeout T3	688	60
!AGV Communications Timeout T4	689	60
!AGV Communications Timeout T5	690	60
!Autodeletion of system data time	692	60
!Implant Start Pressure	693	0.00006
!Implant Stop Pressure	694	0.0001
!SECS Cassette Table Log Format	695	1
!Loadlock Auto-Clean # Cycles	697	10
!Co_Gas Enable	3611	
!Mo contamination test threshold	3615	0.1
!W contamination test threshold	3616	0.1
!Process Chamber Autoclean Cycles	3619	5
!GEM Process Recipe Type	3622	
!GEM Binary Data Log Options	3629	
!GEM Protocol type	3638	
!GEM/HSMS IP Address	3639	192.168.15.25
!GEM/HSMS TCP Port	3640	5000
!GEM/HSMS T5 Timeout	3641	5
!GEM/HSMS T6 Timeout	3642	10
!GEM/HSMS T7 Timeout	3643	5

!GEM/HSMS T8 Timeout	3644	6
!GEM/HSMS Connection Establishment Timeout	3645	5
!GEM/HSMS Circuit Assurance Timeout	3646	
!GEM/HSMS TGRACE Timeout	3647	15
!GEM/HSMS Memory Stall Timeout	3648	5
!GEM/HSMS Write Stall Timeout	3649	7
!X contamination test threshold	3650	0.1
!Logfile Management 01	3651	None
!Logfile Management 02	3652	None
!Logfile Management 03	3653	None
!Logfile Management 04	3654	None
!Logfile Management 05	3655	None
!Logfile Management 06	3656	None
!Logfile Management 07	3657	None
!Logfile Management 08	3658	None
!Folder Selection	701	1
!Recipe Locking	702	1
!Print implant log at the end of every n-th implant	703	
!SPC2 Present	704	
!Limits Monitor Interval	709	10
!Max Number of Messages to Transmit for a S6F23	710	
!Spooling Enabled	711	
!Over Write Spool when Full	712	
!GEM Off-Line Substate	713	1
!GEM Off-Line Fail Substate	714	1
!GEM On-Line Substate	715	4
!GEM Version E30-92 E30-95	716	
!GEM Time Format	717	
!GEM Add Cassette MID Only	718	
!GEM MIR, MIC, MOR, MOC Events	719	
!Cassette BCR Present	720	
!Cassette Sensor Events	721	
!Gasbox DI version / availability	801	1
!Source DI version / availability	802	3
!Beam Line DI version / availability	804	2
!Dose DI version / availability	816	6
!Injector Vacuum DI version / availability	820	1
!Lin. Accel. Vacuum DI version / availability	821	1
!Main Facilities 1 DI version / availability	824	1
!Main Facilities 2 DI version / availability	825	1
!Lin. Accel. Air 1 DI version / availability	826	1
!Lin. Accel. Air 2 DI version / availability	827	1
!Final Magnet DI version / availability	831	1

!Ground Power Distrib. DI version / availability	833	1
!Disk Vacuum DI version / availability	835	1
!Disk ThermoCouple DI version / availability	836	1
!Rotary Drive (SEN-)DI version / availability	837	1
!Gyro Drive (SEN-)DI version / availability	838	1
!Vert. Scan Drive (SEN-)DI version / availability	839	
!In Air Wafer Handling (SEN-)DI version / availability	840	1
!In Vacuum Wafer Handling (SEN-)DI version / availability	841	1
!End Sta. Elec. DI version / availability	842	1
!Quadrupole DI version / availability	843	1
!Injector Elec. DI version / availability	844	3
!Injector PD. DI version / availability	845	1
!Water PD DI version / availability	846	
!Resonator Ctl. #1 DI version / availability	847	1
!Resonator Ctl. #2 DI version / availability	848	1
!Resonator Ctl. #3 DI version / availability	849	1
!Resonator Ctl. #4 DI version / availability	850	1
!Resonator Ctl. #5 DI version / availability	851	1
!Resonator Ctl. #6 DI version / availability	852	1
!Resonator Ctl. #7 DI version / availability	853	1
!Resonator Ctl. #8 DI version / availability	854	1
!Resonator Ctl. #9 DI version / availability	855	1
!Resonator Ctl. #10 DI version / availability	856	1
!Resonator Ctl. #11 DI version / availability	857	
!Resonator Ctl. #12 DI version / availability	858	
!Resonator Ctl. #13 DI version / availability	859	
!Resonator Ctl. #14 DI version / availability	860	
!Robot Controller	861	1
!Plasma DI version / availability	863	
!Quadrupole DI #2 version / availability	865	
!Gas line 1 type	1501	2
!Gas line 2 type	1502	5
!Gas line 3 type	1503	5
!Gas line 4 type	1504	5
!Gas line 5 type	1505	
!Gas line 6 type	1506	
!Gas Meter Valve 1 type	1507	32
!Gas Meter Valve 2 type	1508	32
!Gas Meter Valve 3 type	1509	32
!Gas Meter Valve 4 type	1510	32
!Gas Meter Valve 5 type	1511	
!Gas Meter Valve 6 type	1512	
!Gas PG 1 type	1513	48

!Gas PG 2 type	1514	35
!Gas PG 3 type	1515	35
!Gas PG 4 type	1516	35
!Gas PG 5 type	1517	
!Gas PG 6 type	1518	
!Hydrogen Generator Present	1519	
!Monitor H2 Generator during implant	1520	1